

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Seong Deok Ahn et al.

Application No.: 10/672,013

Filed: September 26, 2003

For: **Method and Apparatus Using Large-Area
Organic Vapor Deposition for Formation of
Organic Thin Films or Organic Devices**

Examiner: Richard R. Bueker

Art Unit: 1792

Confirmation No.: 7684

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

In response to the Office Action mailed January 22, 2009, in connection with the above referenced patent application, Applicants respectfully request entry of the following amendments and request reconsideration in view of the following remarks.

Amendments to the claims begin on page 2.

Remarks begin on page 6.